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Filing or 371(c) Date: Filed herewith
First Inventor: David J. SCHROEDER
Title: CHEMICAL-MECHANICAL
POLISHING COMPOSITION AND
METHOD FOR USING THE SAME

Certification under 37 CFR 1.10

I, Mariejose Monsalve hereby certify that this paper is being deposited in an envelope with the U.S. Postal Service "Express Mail Post Office to Addressee" service on 17 FEB 06 and addressed to Mail Stop PCT, Commissioner for Patents, Alexandria, VA, 22313-1450.


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PRELIMINARY AMENDMENT

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This communication is submitted in advance of prosecution on the merits of the above identified patent application.

Amendments to the specification are reflected on page 2 of this paper.

Amendments to the claims are reflected in the listing of claims that begins on page 3 of this paper.

Remarks begin on page 6 of this paper.

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